

**AMENDMENTS TO THE SPECIFICATION:**

Please amend the portions of the specification identified below to read as indicated herein.

**At page 1, preceding line 6, please add the following heading and paragraph:**

**CROSS-REFERENCE TO RELATED APPLICATIONS**

The present application is a U.S. national stage entry under 35 U.S.C. 371, of International Application No. PCT/PH2002/000013, filed July 9, 2002.

**Please amend the paragraph beginning at page 7, line 10 as follows:**

A beam-scanning reflectance microscope was constructed for both 1 P-OBIC and confocal imaging (Fig 1). Via a beam splitter (11), the output beam of laser is directed to a scanning mirror system that is composed of two galvanometer mirrors (General Scanning Model G115) for x (12) and y (13) scanning, and two lenses (L1, L2) (14, 15) that constitute a 4f transfer lens. Another pair of lenses (16, 17) expands and collimates the scanned beam and inputs it to an optical microscope assembly. An infinity-corrected objective lens (4018) focuses the beam into the exposed top surface of the integrated circuit sample (19). The beam is directed using a plane mirror (20). Precise 2D scan control of the focused beam is achieved via a pair of digital-to-analog converters (21).

**Please amend the paragraph beginning at page 7, line 22 as follows:**

The reflected light is collected back by the same objective lens (18) and focused by lens (22) towards a pinhole that is placed in front of photodetector (23). The 1P-OBIC is measured by inputting the output of the pin that is nearest to the probe surface

area to a current-to-voltage converter composed of an operational amplifier and a feedback resistor (24). The other converter input is the common reference (25) for the electronic circuits including the IC sample. A 1P-OBIC signal is induced because the bandgap  $E_b$  is less than the excitation photon energy.